

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **OZAKI**, **Takashi**, et al.

Group Art Unit: 2813

Serial No.: 10/517,765

Examiner: MCCALL SHEPARD, Sony

Filed: February 3, 2006

P.T.O. Confirmation No.: 6791

FOR: SUBSTRATE TREATING APPARATUS AND METHOD FOR MANUFACTURING

SEMICONDUCTOR DEVICE

AMENDMENT UNDER 37 CFR §1.111

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

July 30, 2008

Sir:

In response to the Office Action dated February 5, 2008, extended from May 5, 2008 to August 5, 2008 by a three (3) month Petition for Extension of Time, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.